



Department of
Mechanical Engineering
The University of Hong Kong



SEMINAR

Bottom-up Au electroplating of high-aspect-ratio Si-based X-ray microgratings

Date: 8 April, 2024 (Monday)
Time: 2:00 p.m.
Venue: HW7-32, Haking Wong Building
HKU

Speaker: Dr. Liyang Chen
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Abstract:

Au microgratings with small pitches and high aspect ratios are desired for high-sensitivity X-ray interferometry imaging. We use Au bottom-up filling (BUF) in Si templates to realize high-aspect-ratio Au microgratings. Void-free BUF in low-aspect-ratio gratings is first demonstrated to show BUF progression, and the mechanism of bismuth-stimulated BUF is explained by simulations. Fine tuning of process parameters is needed as a function of grating feature sizes; void-free BUF becomes more challenging when the aspect ratio increases as truncated BUF can occur. Progress to void-free filling of gratings with 2.1- μm -wide and 150- μm -deep trenches (aspect ratio > 70) is reported.

ALL INTERESTED ARE WELCOME

For further information, please contact Prof. W.D. Li at 3917 8982.